



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Abdurrahman Sezginer et al.

PATENT APPLICATION

Serial No.: 10/074,561

Group Art Unit: 2881

Filed: February 12, 2002

Examiner:

For: OVERLAY ALIGNMENT METROLOGY

USING DIFFRACTION GRATINGS

Preliminary Amendment

Hon. Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

Prior to the first Office action, please add the
following new claims.

In the claims:

Please add claims 32 - 40 as follows:

32. (new) The method of claim 1, further comprising observing at least one second test area on said substrate using a camera, the second test area having a pattern built into layers A and B for measuring any gross overlay errors, and wherein determining the offset includes using gross overlay measurements obtained from the camera.

33. (new) The method of claim 32, wherein said pattern in said second test area comprises a box-in-box pattern.

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